

BRS L7 6221 ((coeff\$8 with therm\$6 with expan\$6) or CTE) with silicon
 USPAT; US-PGPUB 2004/01/10 17:34 0
 BRS L8 175 ((coeff\$8 with therm\$6 with expan\$6) or CTE) with silicon with
 value USPAT; US-PGPUB 2004/01/10 17:39 0
 BRS L9 395 ((coeff\$8 with therm\$6 with expan\$6) or CTE) with gold
 USPAT; US-PGPUB 2004/01/10 17:47 0
 BRS L10 15 ((coeff\$8 with therm\$6 with expan\$6) or CTE) same (dielectric\$6
 with (layer\$4 or stack\$6) with mirror) USPAT; US-PGPUB 2004/01/10 18:16
 0
 BRS L11 1 6525880.pn. USPAT; US-PGPUB 2004/01/10 18:09
 0
 BRS L12 1 6525880.pn. and (mirror same coat\$6) USPAT; US-PGPUB
 2004/01/10 18:13 0
 BRS L13 1558 mirror with coat\$6 with dielectric USPAT; US-PGPUB
 2004/01/10 18:14 0
 BRS L14 144 13 and 385/\$.ccls. USPAT; US-PGPUB 2004/01/10 18:14
 0
 BRS L15 46 13 and (mirror same (coeff\$8 with therm\$6 with expan\$6))
 USPAT; US-PGPUB 2004/01/10 18:17 0
 BRS L22 2488 385/16.ccls. or 385/18.ccls. or 385/47.ccls. or 359/578.ccls.
 USPAT; US-PGPUB 2004/01/10 19:10 0

 BRS 0 (MEM with dop\$6 with curv\$6) same mirrorUSPAT 2004/01/09
 10:39 0
 BRS 106 MEM with dop\$6 USPAT 2004/01/09 10:28
 0
 BRS 18 (MEM with dop\$6) and (mirror or relect\$6) USPAT 2003/09/12
 15:23 0
 BRS 1 MEM with dop\$6 with curv\$6 USPAT 2003/09/12 15:23
 0
 BRS 1 ((MEMS or MOEMS) same (mirror\$4 or reflect\$7 or HR)) and ((mirror\$4
 or reflect\$7 or HR) with (micrometer or ".mu."\$8)) and (curvature with radius)
 USPAT 2004/01/08 11:41 0
 BRS 9 ((MEMS or MOEMS) same (mirror\$4 or reflect\$7 or HR)) and ((mirror\$4
 or reflect\$7 or HR) with (micrometer or ".mu."\$8)) and (curvature with radius)
 USPAT; US-PGPUB 2004/01/08 12:54 0
 BRS 1 "20030138213" USPAT; US-PGPUB 2004/01/08 11:51
 0
 BRS 9 ((MEMS or MOEMS) same (mirror\$4 or reflect\$7 or HR)) and ((mirror\$4
 or reflect\$7 or HR) with (micrometer or ".mu.m")) and (curvature with radius)
 USPAT; US-PGPUB 2004/01/08 12:56 0
 BRS 7 (((MEMS or MOEMS) same (mirror\$4 or reflect\$7 or HR)) and
 ((mirror\$4 or reflect\$7 or HR) with (micrometer or ".mu.m")) and (curvature with
 radius)) and ".mu.m" USPAT; US-PGPUB 2004/01/08 12:56 0
 BRS 7 (((MEMS or MOEMS) same (mirror\$4 or reflect\$7 or HR)) and
 ((mirror\$4 or reflect\$7 or HR) with (micrometer or ".mu.m")) and (curvature with

radius)) and "mu.m"\$8 USPAT; US-PGPUB 2004/01/10 17:33
0
BRS 1 6525880.pn. USPAT; US-PGPUB 2004/01/08 14:27
0
BRS 2 (coat\$6 with layer\$6) and (MEMS or MOEMS) and ((process or method) with (mak\$6 or fabricat\$6 or manufactur\$6)) and (etch\$8 with layer\$6) and (dop\$6 with curv\$7) USPAT 2004/01/09 10:14 0
BRS 5 (coat\$6 with layer\$6) and (MEMS or MOEMS) and ((process or method) with (mak\$6 or fabricat\$6 or manufactur\$6)) and (etch\$8 with layer\$6) and (dop\$6 with curv\$7) USPAT; US-PGPUB 2004/01/09 10:15 0
BRS 8 (coat\$6 with layer\$6) and (MEMS or MOEMS) and ((process or method) with (mak\$6 or fabricat\$6 or manufactur\$6)) and (etch\$8 with layer\$6) and (dop\$6 with curv\$7) USPAT; US-PGPUB 2004/01/09 10:16 0
BRS 1 ((MEM or MOEM) with dop\$6) with ((curv\$6 or bend\$6) with (substrat\$6 or wafer\$6)) USPAT 2004/01/09 10:45 0
BRS 510 (coat\$6 with layer\$6) and (MEMS or MOEMS) and ((process or method) with (mak\$6 or fabricat\$6 or manufactur\$6)) and (etch\$8 with layer\$6) USPAT 2004/01/09 10:31 0
BRS 1005 (coat\$6 with layer\$6) and (MEMS or MOEMS) and ((process or method) with (mak\$6 or fabricat\$6 or manufactur\$6)) and (etch\$8 with layer\$6) USPAT; US-PGPUB 2004/01/09 10:45 0
BRS 22 (MEMS or Moems) and (dop\$6 with curvature) USPAT; US-PGPUB 2004/01/09 10:40 0
BRS 161 (coat\$6 with layer\$6) and (MEMS or MOEMS) and ((process or method) with (mak\$6 or fabricat\$6 or manufactur\$6)) and (etch\$8 with layer\$6) and ((curv\$6 or bend\$6) with (substrat\$6 or wafer\$6)) USPAT; US-PGPUB 2004/01/09 11:07
0
BRS 123 ((coat\$6 with layer\$6) and (MEMS or MOEMS) and ((process or method) with (mak\$6 or fabricat\$6 or manufactur\$6)) and (etch\$8 with layer\$6) and ((curv\$6 or bend\$6) with (substrat\$6 or wafer\$6))) and (mirror\$4 or reflect\$8) USPAT; US-PGPUB 2004/01/09 11:07 0
BRS 51 ((coat\$6 with layer\$6) and (MEMS or MOEMS) and ((process or method) with (mak\$6 or fabricat\$6 or manufactur\$6)) and (etch\$8 with layer\$6) and ((curv\$6 or bend\$6) with (substrat\$6 or wafer\$6))) and (mirror\$4 or reflect\$8) and (dop\$6 same substrate) USPAT; US-PGPUB 2004/01/09 11:25 0
BRS 25 ryf.in. USPAT; US-PGPUB 2004/01/09 14:09 0
BRS 1 5618474.pn. USPAT; US-PGPUB 2004/01/09 14:09
0